December 16, 2004



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: KAWAGUCHI et al

Serial No.: 10/083,252

Filed: February 27, 2002

For: Plasma Processing Method And Apparatus

Art Unit: 1763

Examiner: P. Hassanzadeh

## <u>AMENDMENT</u>

Mail Stop: Amendment (Fee) Commissioner For Patents P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application and accompanies the RCE. The amendments are listed below and set forth on the following pages.

Amendments to the Claims; and

Remarks are included following the amendments.